

## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Syo-ichi TAKAMIZAWA et al.

Group Art Unit: 1792

Application No.: 10/578,369

Examiner:

R. Kunemund

Filed: May 5, 2006

Docket No.:

127101

For:

METHOD FOR PRODUCING SILICON EPITAXIAL WAFER

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the March 25, 2008 Office Action, the period for reply being extended by the attached Petition for Extension of Time, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and Remarks.